SEE ATOMS IN MOTION!

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It is impressive enough that individual atoms can be resolved with the atomic force microscope (AFM), but who would have thought that atomic motion would be detected so soon? Atomic resolution with the AFM was only recently achieved. As reported in this column,[2] Franz Giessibl[3] was able to demonstrate local resolution of adatoms of the Si(111) 7X7 reconstructed surface. Now, Yasuhiro Sugawara, Masahiro Ohta, Hitoshi Ueyama, and Seizo Morita of Hiroshima University have demonstrated atomic resolution of the surface of InP(110).[4] Not only that, but images taken about one minute apart show that some of the atoms had moved! Sugawara *et al.* used a very compact AFM under ultrahigh vacuum (4×10^{-8} Pa) to accomplish this impressive feat. A stiff (spring constant of 34 N/m) silicon cantilever was used. This stiffness, along with a mechanical resonant frequency of 151 kHz, was used to keep the cantilever from jumping onto the sample and crushing the initially sharp tip. The cantilever was scanned by a tube piezoelectric scanner, and its deflection was detected by a very sensitive optical-fiber interferometer. The frequency modulation (FM) detection method was used in the non-contact mode to measure the force gradient acting on the tip. The scanner was also used to vibrate the cantilever at the mechanical resonant frequency. A positive feedback system with automatic gain control was used to maintain a constant vibration amplitude of 20 nm. The frequency shift of the cantilever was detected by a tunable analog FM demodulator. The images were obtained at room temperature at a constant force gradient; they kept the distance between the tip and the sample constant by maintaining a constant frequency shift of -6 Hz.

In their published micrographs, Sugawara *et al.* clearly demonstrated the rectangular lattice of the InP(110) surface. Because they used the non-contact mode, they were able to avoid the distortion caused by friction between the tip and sample that is seen in the contact mode. The lattice structure represents rows of quasi-one-dimensional zigzag chains of alternating phosphorus and indium atoms. The distance between phosphorus atoms along the chain was measured at 0.43 nm and the distance between chains was 0.58 nm, in good agreement with accepted values.

Most impressive was the visualization of defects referred to as "P vacancies," thought to be caused by cleavage of the sample. Occasionally, the sites of these missing phosphorus atoms were seen in small groups, and when images were taken about 80 seconds apart, the defects had moved over a row or two, relative to each other. In one case, a single defect became two. This suggests that phosphorus atoms are moving between chains on a time frame of a minute or so.

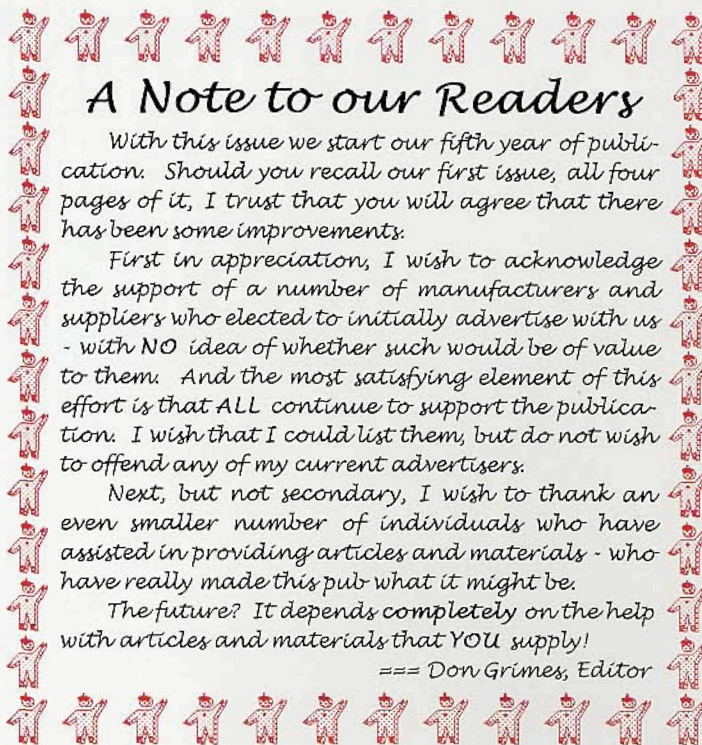
The advantages of demonstrating this thermal motion with AFM, rather than scanning tunneling microscopy (STM), was discussed by Sugawara *et al.* The main point is that with STM the atoms may be influenced by tip-induced effects that are absent in the AFM. While the evidence suggests that these observations are of thermally-induced atomic motion, other mechanisms could not be excluded. Nevertheless, this demonstration of atoms in motion remains quite impressive!

1 The author gratefully acknowledges Yasuhiro Sugawara, for reviewing this article.

2 Atomic resolution with the atomic force microscope, *Microscopy Today*, 95-4 6, 1995.

3 Giessibl, F., Atomic resolution of the silicon (111)-(7X7) surface by atomic force microscopy, *Science* 267:68-71, 1995.

4 Sugawara, Y., M. Ohta, H. Ueyama, and S. Morita Defect motion on an InP(110) surface observed with noncontact atomic force microscopy, *Science* 270:1646-1648, 1995



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=== Don Grimes, Editor

Front Page Image

SEM Photograph of A Marine Mite Feeding On a Mystacocarid (Typica) - Marine Meiofauna

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https://doi.org/10.1017/S155192950006692X Published online by Cambridge University Press

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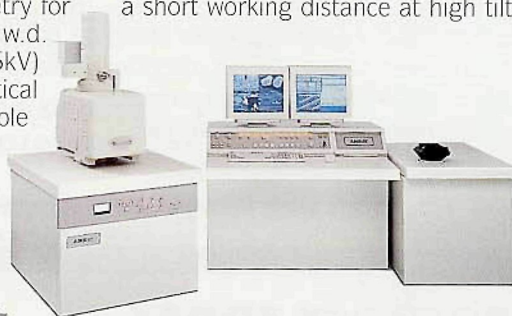

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